

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hiroyuki KANBARA et al. Application No.: 10/596,000 Confirmation No.: 1561 Filing or 371(c) Date: January 17, 2007 Title: METHOD FOR FORMING THICK FILM PATTERN, METHOD FOR MANUFACTURING ELECTRONIC COMPONENT AND PHOTOLITHOGRAPHY PHOTOSENSITIVE PASTE.	Art Unit: 1795  Examiner: A. Eoff
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**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated October 10, 2007, please amend the above-identified application as follows:

- ☐ **Amendments to the Specification** begin on page      of this paper.
- ☒ **Amendments to the Claims** are reflected in the listing of the claims which begins on page **2** of this paper.
- ☐ **Amendments to the Drawings** begin on page      of this paper and include an attached replacement sheet. An **Appendix** including the amended drawing figures is attached following page      of this paper.
- ☒ **Remarks/Arguments** begin on page **6** of this paper.

Please note, if a box is not checked, then no corresponding amendment is being made.